



Form PTO-1449 (Modified) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	Atty. Docket No.: F0611	Serial No.: 09 903,884
	Applicants: Halliyal, et al.	
	Filing Date: July 12, 2001	Group: 2877

REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Partial Translation	
						Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

	<i>NS</i>	Niu, X., et al., "Specular Spectroscopic Scatterometry in DUV Lithography," Timbre Technology, Inc., et al.
	<i>NS</i>	Smith, T., et al., "Process Control in the Semiconductor Industry," http://www.mit.edu/taber/Research/Process_Control/IFRC99 pp1-24.
	<i>NS</i>	Cote, D.R., et al., "Plasma-assisted chemical vapor deposition of dielectric thin films for ULSI semiconductor circuits," IBM Journal of Research & Development, Vol. 43, No. 1, pp 1-30.

EXAMINER 	DATE CONSIDERED 2 July 2003
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Information Disclosure Statement PTO-1449 (Modified)

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